UNITE	ED ST	ATES I	PATEN	T AND	TRAI	DEMA1	RK OF	FICE
BEFO	ORE T	HE PA	TENT 7	ΓRIAL .	AND A	APPEA	L BO	ARD

TAIWAN SEMICONDUCTOR MANUFACTURING COMPANY, LTD., TSMC NORTH AMERICA CORPORATION, FUJITSU SEMICONDUCTOR LIMITED, FUJITSU SEMICONDUCTOR AMERICA, INC., ADVANCED MICRO DEVICES, INC., RENESAS ELECTRONICS CORPORATION, RENESAS ELECTRONICS AMERICA, INC., GLOBALFOUNDRIES U.S., INC., GLOBALFOUNDRIES DRESDEN MODULE ONE LLC & CO. KG, GLOBALFOUNDRIES DRESDEN MODULE TWO LLC & CO. KG, TOSHIBA AMERICA ELECTRONIC COMPONENTS, INC., TOSHIBA AMERICA INC., TOSHIBA AMERICA INFORMATION SYSTEMS, INC., TOSHIBA CORPORATION, and THE GILLETTE COMPANY, Petitioners,

V.

ZOND, LLC, Patent Owner

Patent 7,811,421 B2

IPR Case Nos. IPR2014-00800, 00802, 00805

DECLARATION OF LAWRENCE J. OVERZET PH.D. ON BEHALF OF PETITIONER



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J.	Dependent Claims 6, 31, and 45: "a gas flow controller that controls a flow of the feed gas so that the feed gas diffuses the strongly-ionized plasma"
K.	Dependent Claim 44: "diffusing the weakly-ionized plasma with a volume of the feed gas while ionizing the volume of the feed gas to create additional weakly-ionized plasma"
L.	Dependent Claims 7 and 32: "the gas flow controller controls the flow of the feed gas to allow additional power to be absorbed by the strongly ionized plasma, thereby generating additional thermal energy in the sputtering target"



- I, Lawrence J. Overzet, declare as follows:
 - 1. My name is Lawrence J. Overzet.
- 2. I received my bachelors, masters, and Ph.D. in electrical engineering, all from the University of Illinois, College of Engineering, Urbana, IL. My doctoral thesis was titled "Enhancement of the Negative Ion Flux to Surfaces from Radio Frequency Processing Discharges."
- 3. Since graduating in 1988, I have worked as a professor in the Department of Electrical Engineering at the University of Texas at Dallas. I have taught many courses including Introduction to Electromagnetic Fields I and II; Plasma Processing Technology; Plasma Science for Materials Processing; and Current Topics in Plasma Processing.
- 4. I have written over 75 articles, presented over 240 presentations at international symposia, and have 8 patents in various areas of electrical engineering, most of which being related to plasma science.
- 5. I am a senior member of the Institute of Electrical and Electronic Engineers (IEEE), and am a fellow of the American Vacuum Society (AVS) for my contributions toward understanding pulsed plasmas and the role of negative ions in plasma processing.
 - 6. A copy of my resume is provided as Appendix A to this declaration.



- 7. I have reviewed the following publications in preparing this declaration:
 - U.S. Patent No. 7,811,421 (the "'421 Patent") (Ex. 1001)).
 - D.V. Mozgrin, et al, <u>High-Current Low-Pressure Quasi-Stationary</u>
 <u>Discharge in a Magnetic Field: Experimental Research</u>, Plasma Physics
 Reports, Vol. 21, No. 5, pp. 400-409, 1995 ("Mozgrin" (Ex. 1003)).
 - U.S. Pat. No. 6,413,382 ("Wang" (Ex. 1004)), including U.S. Pat. No. 6,398,929 ("Chiang" (Ex. 1009)) which is incorporated by reference by Wang.
 - U.S. Pat. No. 6,190,512 ("Lantsman" (Ex. 1005)).
 - D.V. Mozgrin, <u>High-Current Low-Pressure Quasi-Stationary Discharge in a Magnetic Field: Experimental Research</u>, Thesis at Moscow Engineering Physics Institute, 1994 and Certified Translation ("Mozgrin Thesis" (Ex. 1207 and 1208)).
 - U.S. Patent No. 7,808,184 (Ex. 1032)
- 8. I have read and understood each of the above publications and any other publication cited in this declaration. The disclosure of each of these publications provides sufficient information for someone to make and use the plasma generation and sputtering processes that are described in the above publications.



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